

L Number	Hits	Search Text	DB	Time stamp
1	111013	position near3 sens\$3	USPAT; US-PGPUB	2003/10/29 11:31
3	4	(position near3 sens\$3) same (electrical\$3 near3 (decoupl\$3 or isolat\$3) near3 (capacit\$4))	USPAT; US-PGPUB	2003/10/29 11:14
4	68444	position near3 sens\$3	EPO; JPO; DERWENT	2003/10/29 11:13
5	2	(position near3 sens\$3) same (electrical\$3 near3 (decoupl\$3 or isolat\$3) near3 (capacit\$4))	EPO; JPO; DERWENT	2003/10/29 11:15
6	0	(mass or weight) same (electrical\$3 near3 (decoupl\$3 or isolat\$3) near3 (capacit\$4))	EPO; JPO; DERWENT	2003/10/29 11:54
7	11	(mass or weight) same (electrical\$3 near3 (decoupl\$3 or isolat\$3) near3 (capacit\$4))	USPAT; US-PGPUB	2003/10/29 13:14
8	0	(position near3 sens\$3) same (dielectric near3 trench)	USPAT; US-PGPUB	2003/10/29 11:52
11	23	(electrical\$3 near3 (decoupl\$3 or isolat\$3)) with (MEMS or microfabrat\$3 or micromechanical\$3 or micromachin\$3 or microelectromechanical)	EPO; JPO; DERWENT	2003/10/29 12:06
12	2	(electrical\$3 near3 (decoupl\$3 or isolat\$3) near3 (capacit\$3)) with (MEMS or microfabrat\$3 or micromechanical\$3 or micromachin\$3 or microelectromechanical)	EPO; JPO; DERWENT	2003/10/29 13:11
13	5	(electrical\$3 near3 (decoupl\$3 or isolat\$3) near3 (capacit\$3)) with (MEMS or microfabrat\$3 or micromechanical\$3 or micromachin\$3 or microelectromechanical)	USPAT; US-PGPUB	2003/10/29 13:13
14	629	73/514.32	USPAT; US-PGPUB	2003/10/29 13:11
15	0	73/514.32 and (electrical\$3 near3 (decoupl\$3 or isolat\$3) near3 (capacit\$3))	EPO; JPO; DERWENT	2003/10/29 13:12
16	0	73/514.32 and ((decoupl\$3 or isolat\$3) near3 (capacit\$3))	EPO; JPO; DERWENT	2003/10/29 13:12
17	1707	position near3 interface	EPO; JPO; DERWENT	2003/10/29 13:13
18	0	(position near3 interface) with (MEMS or microfabrat\$3 or micromechanical\$3 or micromachin\$3 or microelectromechanical)	USPAT; US-PGPUB	2003/10/29 13:14
19	0	(position near3 interface) and (electrical\$3 near3 (decoupl\$3 or isolat\$3) near3 (capacit\$4))	USPAT; US-PGPUB	2003/10/29 13:14
20	0	(position near3 interface) and (MEMS or microfabrat\$3 or micromechanical\$3 or micromachin\$3 or microelectromechanical)	USPAT; US-PGPUB	2003/10/29 13:14